

Docket No.: 87391.01000
Customer No. 30734

PATENT/OFFICIAL



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of :
Wen-Jian LIN et al. :
Serial No. 10/815,947 :
Filed: April 2, 2004 :

For: INTERFEROMETRIC MODULATION PIXELS AND
MANUFACTURING METHOD THEREOF

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

No further elaboration is believed necessary. Copies of the documents are submitted herewith in accordance with 37 C.F.R. §1.98(a).

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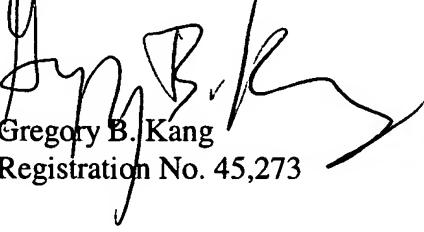
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AUTHORIZATION

This Information Disclosure Statement is being filed before receipt of the first Office Action.
No fee is required. The Commissioner is hereby authorized to charge any additional fees which may
be required for this submission, or credit any overpayment to deposit account no. 50-2036.

Respectfully submitted,

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Date: April 28, 2004

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LIST OF ART CITED BY APPLICANT

(PTO-1449)

ATTY. DOCKET NO.
87391.1000

SERIAL NO.
10/815,947

APPLICANT
Wein-Jian LIN et al.

FILING DATE
04/02/04

GROUP

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
A	5,835,255	11/10/98	MILES	359	291	05/05/94
B						
C						
D						
E						
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FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation
U						
V						
W						
X						
Y						
Z						
AA						
BB						
CC						
DD						
EE						
FF						
GG						

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

HH	
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MM	
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EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.